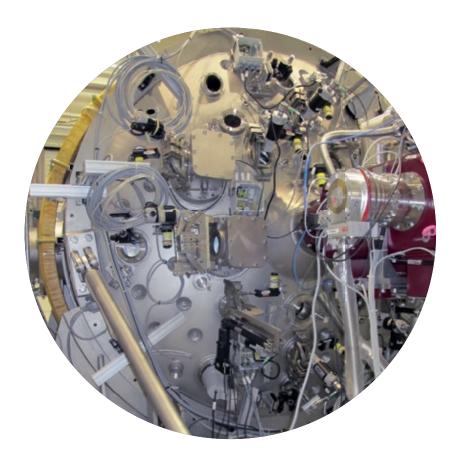
VAKUUM SERVIS

Vacuum is nothing but everything for us.



VACUUM TECHNOLOGY, VACUUM EQUIPMENT PRODUCTION

Vakuum servis s.r.o. is authorized service center of Pfeiffer Vacuum, and also a representative of VAT Vakuumventile AG, SPECS Gmbh, scia Systems and HSR AG for the Czech and Slovak Republic. The company has been operating for more than 30 years in the field of vacuum technology, vacuum deposition and helium leak detection. The company is also engaged in sales of vacuum equipment, servicing of rotary, dry, turbo and diffusion vacuum pumps, design and manufacturing of various vacuum systems, and helium leak detection systems.

Service Center

Service of Pfeiffer Vacuum and Adixen rotary, turbomolecular and oil-free vacuum pumps. Service of Balzers, Pfeiffer Vacuum, etc. Service of quadrupole analyzers, leak finders and other vacuum components Pfeiffer Vacuum, Adixen, Balzers, etc. Service of vacuum valves by VAT Vacuumventile AG, Service of cryogenic and diffusion pumps (HSR AG)

Vacuum Equipment

Design, development and production of vacuum furnaces, coating systems, industrial HLDS, customized vacuum systems. Refurbishment of Balzers BAK, LL801 and other vacuum systems.

Leak detection, analysis

Leak detection in vacuum equipment with helium leak detector. Analysis of vacuum equipment with quadrupole analyzer.

Business activities

Sales of rotary oil pumps, dry pumps, Pfeiffer Vacuum and Adixen turbomolecular pumps. Sales of cryogenic and diffusion pumps from HSR AG. Exclusive sales of VAT vacuum valves. Supply of vacuum components. Supply of spare parts for vacuum equipment. Sales of used and reconditioned vacuum components and equipment. Exclusive representation of the company VAT Vakuumventile AG for the Czech and Slovak Republics.



Vakuum servis s.r.o.

- Design and construction of vacuum pumping stations, vacuum furnaces, helium leak detection systems, vacuum coating systems
- Refurbishment and upgrade of vacuum production systems
- Assembly of vacuum systems as key-turn customized solutions according to individual needs
- Authorised Pfeiffer Vacuum service center



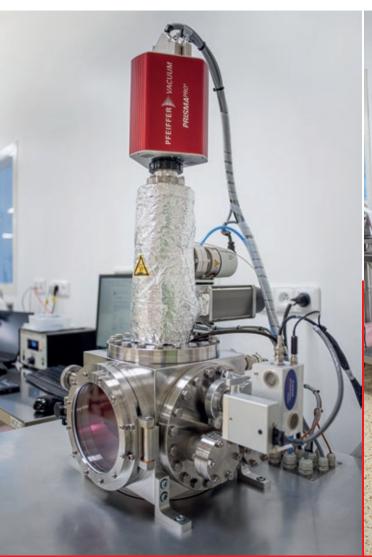
Plasma cleaning device with RGA Analysis



RGA 160 testing system

Main characteristics

- Multipurpose testing device for RGA analysis of UHV components.
- Quantitative outgasing analysis for hydrocarbons, water vapour and other specific chemicals, based on customer needs.
- Measurement method based on ASML standard GSA 07 2221
- Dedicated control software with fully automated measurement cycle with final acceptance protocol in pdf form.
- Possibility of final plasma cleaning and vacuum bakeout of vacuum components before measurement.





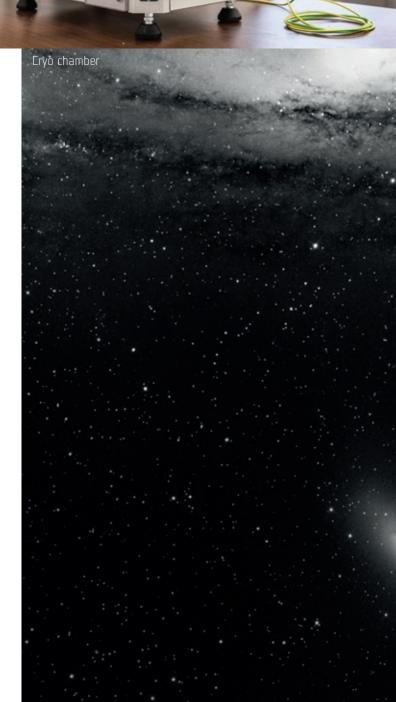


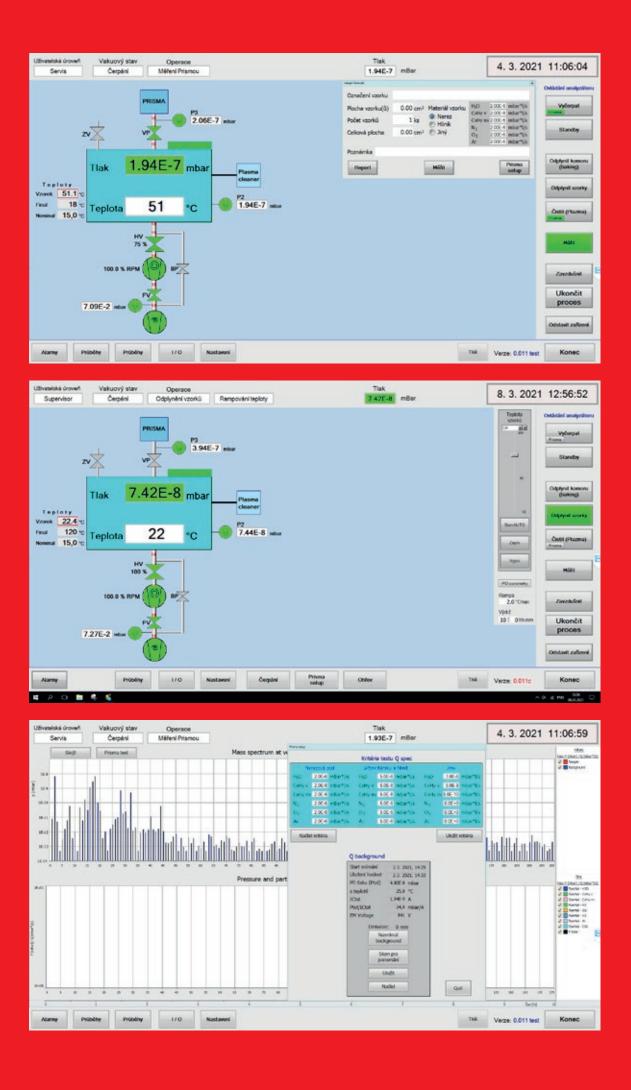
Technical details — standard version

- Oil-free vacuum pumping system with trubomolecular pump and primary scroll pump
- UHV DN160 CF cubical chamber with internal volume of 7 litres
- All-metal vacuum valves
- Quadrupole mass spectrometer Pfeiffer Prisma Pro, mass range 0-200 amu, Faraday +C-SEM detector, open type ion source with Y203 iridium filaments
- Calibration gas mixture included
- Integrated heating for automated system bakeout, (temperature can be adjusted up to 130 °C)
- Ultimate pressure up to < 5e-9 mbar (for empty chamber, after 24 hrs bakeout)
- Minimal detectable leakrate < 5e-7 mbar.l.s-1 for H2O;
 Se-10 mbar.l.s-1 for CxHy
- Footprint 850×750 mm

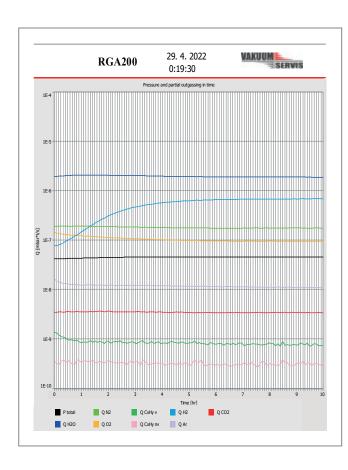
Customization possibilities:

- Enlargement of a speciemen chaber up to 40 liters
- Dedicated pumping system for quadrupole analyzer better stability of measurement performance
- Plasma cleaning unit helps to keep the system in pristine condition free from hydrocarbons





VAKUUM SERVIS 29. 4. 2022 **RGA200** 0:19:30 Batch information Marked as: Test vak Note: pred testem peaky pritomne, perioda cca 50min Quantity: 1 pcs Surface 1 pc: 0 cm² Total Surface: 0.00 cm² **Device information** QMG 250 PRISMA PRO Serial number of Electronics: 44529302 Serial number of Senzor: 44529276 Pump speed: 95 l/s **RESULT SUMMARY** Sample(s) analyze Start Pump 27.4. 2022, 9:28 ICtot: 1.52E-8 A Start RGA time: 28.4. 2022, 14:23 Ptot: 4.46E-8 mbar Qualification time: 29.4. 2022, 0:19 (9:55) Ptot / ICtot: 2,9 mbar/A Report: Test vak peaku_prazd-2022_04_28-14:23 EM Voltage: 1320 V Temperature: 25,5 °C Background information Start Pump 2.3. 2022, 6:45 1.99E-8 A ICtot: Start RGA time: 2.3. 2022, 7:00 Ptot: 3.44E-8 mbar Qualification time: 2.3. 2022, 16:58 (9:57) Ptot / ICtot: 1,7 mbar/A EM Voltage: 1320 V Temperature: 25,6 °C



RGA200 29. 4. 2022 0:19:30 VAKUUM SERVIS

Outgas Values

	Qmeasured [mbar*l/s]	Qbackground [mbar*l/s]	Qbatch [mbar*l/s]		Acceptance factor *)		t spec [h:mm]	t LDL [h:mm]
H ₂ O	1.85E-6	1.18E-6	1.18E-6	2.00E-6	0.59	Inf	31:28	29:09
CxHy v	7.32E-10	2.31E-9	2.31E-9	/ 2.00E-6	< 0.01	Inf	29:09	29:09
CxHy n	3.28E-10	2.32E-10	2.32E-10	《 0.00E+0	****.**	Inf	-	29:09
N ₂	1.72E-7	2.35E-7	2.35E-7	/ 2.00E-6	0.12	Inf	29:09	29:09
02	9.35E-8	1.45E-7	1.45E-7	< 0.00E+0	****.**	Inf	-	29:09
Ar	1.08E-8	1.09E-8	1.09E-8	《 0.00E+0	****.**	Inf	-	29:09

A factor 2 out of specification is accepted to avoid 'false Negative' conclusions

ICtot Sum of Ion Current in the RGA

Ptot Total Pressure within the Chamber

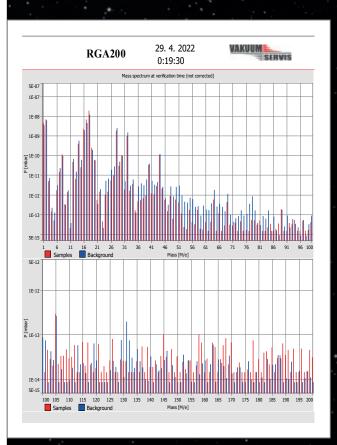
EM Electron Multiplier

Q Outgas rate

 $t\,spec\quad \text{The time between the start of the pump down and the third outgas value in a row lower then the specification value}\\$

LDL Low Detection Limit is two times of background level

Example of protocol



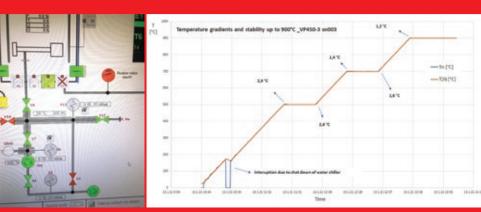
Industrial UHV degassing furnace VSF450

Professional heat treatment of materials for semiconductor industry

- High quality UHV degassing system developed for Pfeiffer Vacuum Austria
- Ultra purity of your materials after degassing
- Suitable for heat treatment of different materials in UHV up to 1300°C (degassing, vacuum soldering, annealing, etc.)
- Ultimate vacuum in heated chamber dia $450 \times 600\,\text{mm}$ better then $8 \cdot 10^{-8}\,\text{mbar}$
- Pfeiffer Vacuum Oil-free pumping system with Scroll and Turbomolecular pump
- Molybdenium heating system designed by Plansee
- Achieved temperature setpoint precision 2°C
- Configurable up to 3 heating zones
- Siemens Simatic control system with touch screen
- Fully configurable system (dimensions, parameters, etc.)



UHV degassing furnace VSF450





Achieved vacuum

Temperature gradient

Model of system



UHV furnace model HVF 4560

Vakuum Servis VSS Classic series

- Universal Customized High Vacuum Evaporation and Sputtering System with flexible technology for Production Research and Development
- Continuous developement of proven Pfeiffer Vacuum Classic system series



VSS Classic 580

- Multi-purpose coating system for general vacuum experiments in the development field, and small-series production
- Heatable Stainless steel chambers with volumes from 35 to 1300 l, inner diameter 250 to 600 mm (other on request), bell jar also possible
- Evaporation and Sputtering from both sides (tilting of sample)
- Various pumping stations available (Turbo-, cryo- or oil diffusion pumps)
- \bullet Final pressures $<5\cdot10^{-7} mbar$ Integral leak rate $<1\cdot10^{-5} mbar$ l/s

Available Sources:

- Resistance evaporators (2 6 kVA)
- Electron beam evaporators (3 15 kW) with single- or multi-pocket crucible
- Ion beam sources (IAD)
- RF and DC sputter cathodes (0.3 10 kW) 2" or 4"





Sources view



Classic 570L

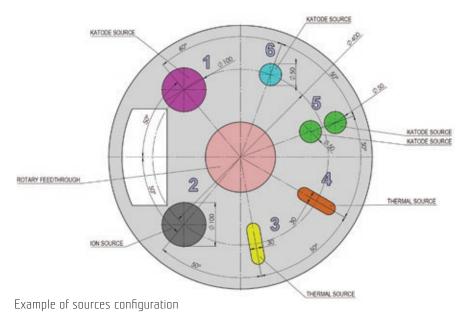
Evaporation:

Anti-reflective process, Scratch resistant process, Laser mirrors, Contact metalization, Deposition of alloys (Co-evaporation)

Sputtering:

Suitable for layers: Metal layers (Au, Cu, Al, Cr, ...), Dielectric layers (SiO2, Al2O3, ...) Transparent, conductive layers (ITO) Magnetic layers Deposition of alloys (co-sputtering)

Various pumping stations available (Turbo-, cryo- or oil diffusion pumps) Vacuum chambers coolable and heatable Final pressures < $5\cdot 10^{\text{-7}}\,\text{mbar}$ Integral leak rate < $1\cdot 10^{\text{-5}}\,\text{mbar}$ l/s



Control system:

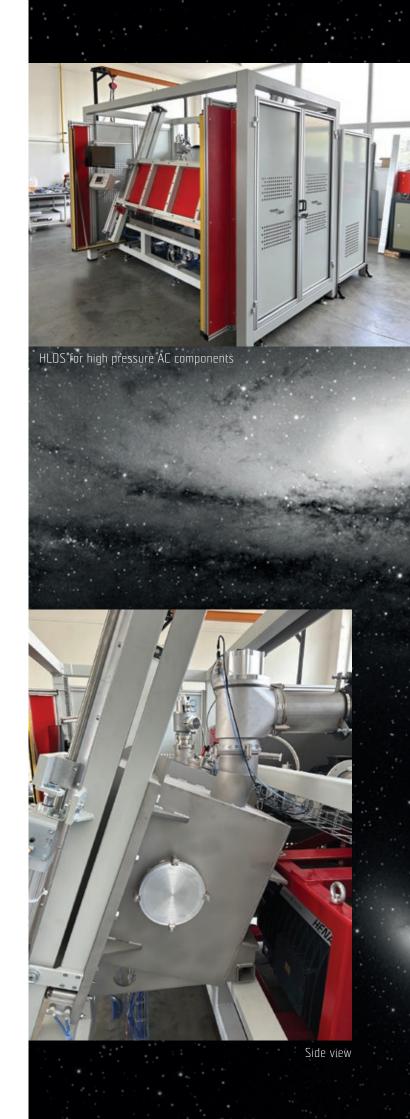
- PLC and industrial PC with visualisation under Windows, Remote acces, Connection to MES
- Fully automatic process control with imple management of recipes
- Detailed data logging (alarm and process archive + trending)

Helium Leak Detection Systems by Vakuum Servis

- State-of-the-art HLDS for automotive and HVAC customers.
- 30 years of experience with HLDS
- High sensitivity in detecting of smallest leaks Equipped with Pfeiffer Vacuum Leak detectors ASM 340, ASI35, ASM 306 etc.
- Fully or semi automated solution, production line integration, high cycle time
- Integral vacuum test, Bombing test, Sniffing test



Visualisation and chamber inside





Parallel HLDS configuration for Valve leak testing



Backside view



Integration into Robotic line

Typical apllications:

airbag detonators testing, air conditioning and fuel system components, valves, etc.

• Selected customers: Hanon, Kayaku Safety system, Bosch, Honeywell, Danfoss, Tl Automotive, Carrier, Kendrion, Stant

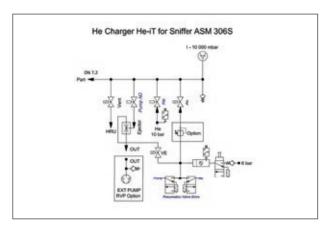


SNIFFING SET - ASM 306S & He CHARGER He-iT

He-It Helium charger

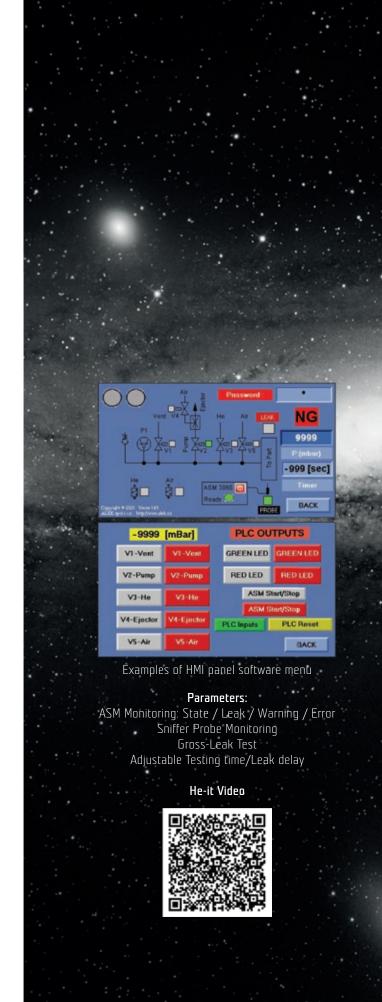
Helium charger for Pfeiffer Vacuum ASM 306S helium leak detector...

He CHARGER He-iT – Smart and Easy Solution for He Sniffing Automatic Helium charging and discharging of the part / ASM monitoring.





START/STOP Button & 4,3" HMI Touch Panel









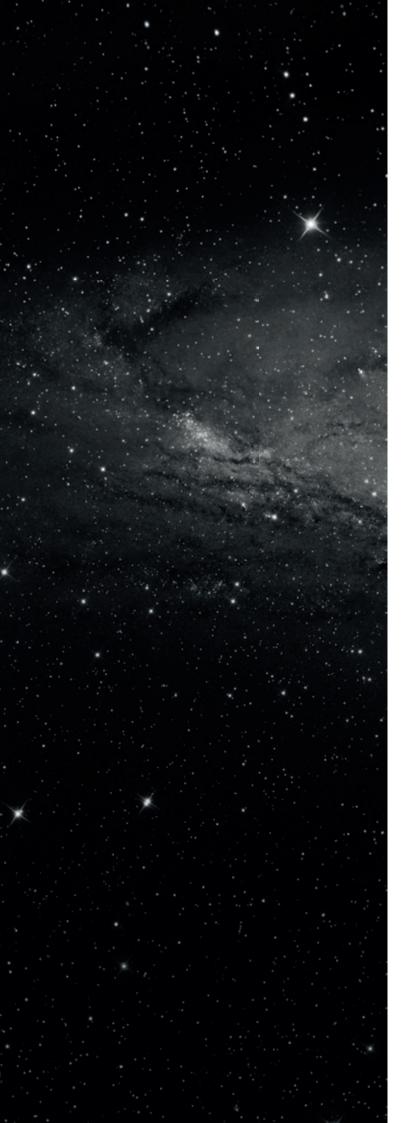








Our distributor in Asia is WESi Technology www.wesitechnology.com



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is the service center of Pfeiffer Vacuum, and is also the sales representative of VAT Vacuumventile, SPECS Gmbh, HSR AG and scia Systems for the Czech and Slovak Republic.

